

PATENT APPLICATION
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q87270

Tsunehisu NAMIKI, et al.

Appln. No.: 10/530,357

Group Art Unit: 3742

Confirmation No.: 7770

Examiner: Quang T. VAN

Filed: September 23, 2005

For: **METHOD OF FORMING A METAL OXIDE FILM AND MICROWAVE POWER
SOURCE DEVICE USED FOR THE ABOVE METHOD**

DECLARATION UNDER 37 C.F.R. § 1.132

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

We, Tsunehisu Namiki, Toshihide Ieki, Hideo Kurashima, Hajime Inagaki, Akira

Kobayashi and Koji Yamada, do declare and state that:

We are all of the co-inventors of the invention disclosed and claimed in our above-identified application. We are also co-inventors of U.S. Patent 6,818,310.

We alone invented the subject matter disclosed at col. 2, lines 18-25; at col. 7, lines 34-50 and at col. 13, lines 36-48 but not claimed in U.S. Patent 6,818,310. Specifically, our invention disclosed but not claimed in U.S. Patent 6,818,310 is directed to a method of forming a metal oxide having a gas-barrier property on a surface of predetermined substrate by plasma CVD using a treatment gas which contains a gas of an organometal and an oxidizing gas. The method of our invention comprises executing a low power glow discharge so as to carry out a reaction chiefly between organometals contained in the treatment gas and thereby form a first CVD film

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on the surface of the substrate, and executing a high power glow discharge so as to react the organometal with the oxidizing gas and thereby form a second CVD film on the first CVD film.

Miwako Tanikawa, a co-inventor of U.S. Patent 6,818,310, did not invent the subject matter of our above-identified application. We are the sole inventors of the invention disclosed and claimed in our above-identified application.

We declare further that all statements made herein of our own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and that such willful false statements may jeopardize the validity of the application or any patent issuing thereon.

Date: Feb. 4, 2008

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Date: Feb. 4, 2008

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Date: Feb. 4, 2008

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